

<b>Notice of References Cited</b>	Application/Control No. 10/677,241	Applicant(s)/Patent Under Reexamination SAKAIDA, HIDEYUKI	
	Examiner Jeffrey S. Smith	Art Unit 2624	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,525,302	02-2003	Dowski et al.	250/201.2
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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	Q					
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	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Akira Ishisaka et al., "A New Method of Analyzing Edge Effect in Phase Contrast Imaging with Incoherent X-rays," Optical Review, Nov/Dec 2000, Vol. 7 Issue 6, pages 566-572
	V	Jan Rakels, "Fourier Analysis of Phase Contrast Microscopy of Nanometric Surfaces," Nanotechnology 4 (1993), pages 230-235
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.